



IFW

## PATENT APPLICATION

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q80074

Eun-sung LEE, et al.

Appln. No.: 10/797,579

Group Art Unit: 1734

Confirmation No.: 4816

Examiner: Michelle A. Lazor

Filed: March 11, 2004

For: SPIN COATING APPARATUS FOR COATING PHOTORESIST

#### AMENDMENT UNDER 37 C.F.R. § 1.111

#### MAIL STOP AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated May 16, 2005, please amend the above-identified application as follows on the accompanying pages.

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